

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Confirmation No. 1660

Shuzo NAGAMI, et. al.

Date: November 2, 2006

Serial No.: 10/693,165

Group Art Unit: 1746

Filed: October 24, 2003

Examiner: Michael KORNAKOV

For: SUBSTRATE PROCESSING APPARATUS AND SUBSTRATE
PROCESSING METHOD

VIA EFS.WEB

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT
REMARKS/ARGUMENT

This Response is filed in reply to the Restriction Requirement mailed October 3, 2006.

Applicant elects the invention of Group I, identified as claims 1-6, drawn to a substrate processing apparatus, classified in class 134, subclass 105.

Applicant reserves the right to file a divisional application directed to the subject matter covered in the non-elected claims.

Early and favorable consideration of the present application is earnestly solicited.

If this communication is filed after the statutory time period had elapsed and no separate Petition is enclosed, the Commissioner for Patents is petitioned, under 37 C.F.R. §1.136(a), to extend the time for filing a response to the outstanding Office Action by the number of months which will avoid abandonment under 37 C.F.R. §1.135. The fee under 37 C.F.R. § 1.17 should be charged to our Deposit Account No. 15-0700.

Respectfully submitted,

THIS CORRESPONDENCE IS BEING
SUBMITTED ELECTRONICALLY
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EFS FILING SYSTEM
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